Complete if Known Substitute for form 1449A/PTO Application Number 10/565,623 INFORMATION DISCLOSURE Filma Date July 25, 2004 STATEMENT BY APPLICANT First Named Inventor Zeev ZALEVSKY Group Art Unit (use as many sheets as necessary) Examiner Name Sheet 1 of 2 Attorney Docket Number ZALEVSKYA

				TENT DOCUMENTS	
			Publication Date MM-DD-YYYY	Name of Palentee or	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
Examiner Initials*				Applicant of Otted Document	
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	NON PATENT LITERATURE DOCUMENTS / OTHER INFORMATION						
Examiner Initials*	Cite No.1	include name of the author (in CAPITAL LETTERS), filte of article (when appropriate), filte of the item (book, magazine, journal, senal, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where publisher.	T ²				
	АН	LEE, H et al. "CMOS chip planarization by chemical mechanical polishing for a vertically stacked metal MEMS integration", Journal of Micromechanics and Microengineering; J.Micromech. Microeng 14 (2004), pp.108-116					
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^{*} EXAMINER: Initial if reference considered, whether or not obtains is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant,

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¹ Applicant's unique citation designation number (optional) ² Applicant is to place a check mark here if English language Translation is attached.